

# XROS MF30

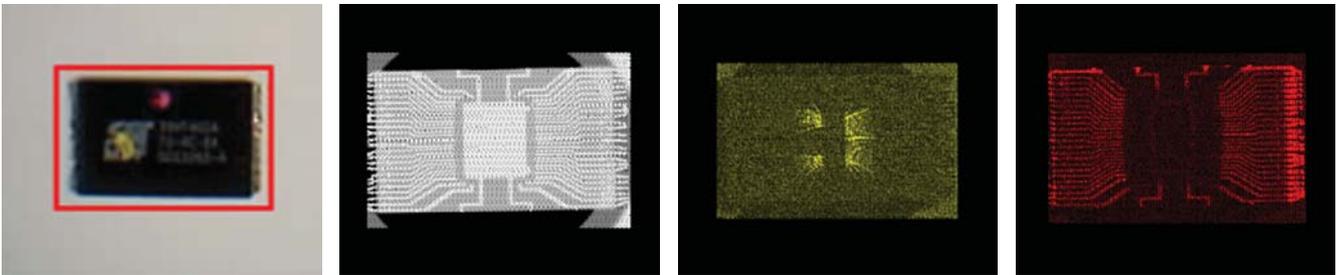
## X-ray analytical microscope-microprobe



XROS MF30 – laboratory x-ray microscope-microprobe for studies of the objects by the methods of the optical microscopy, radiography, local element XRF microanalysis with possibility of the element mapping.

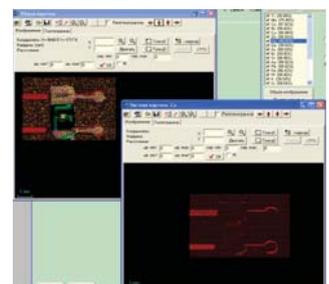
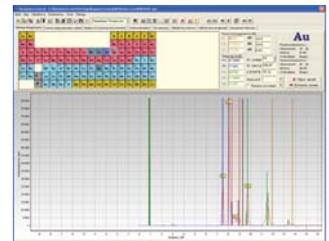
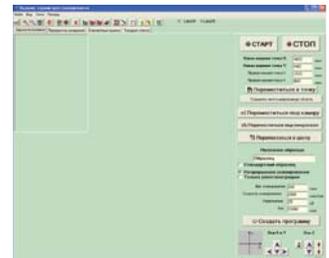
## Instrument features:

- microfocus x-ray tube
- polycapillary lens for making of an x-ray probe with the variable size
- set of primary radiation filters
- video-camera for selection of the analysis area
- optical digital microscope for investigation of the analysis area
- optical microscope axis combined with an x-ray probe axis
- automated system for selection of the work distance
- automated X, Y-coordinate sample stage for positioning and scanning of the analysis area
- automated movement of the analytical unit along Z axis
- detector for radiographic studies
- silicon drift detector for local XRF analysis
- vacuumized measuring chamber for the analysis of light elements
- built-in autonomous system for water cooling of X-ray tube



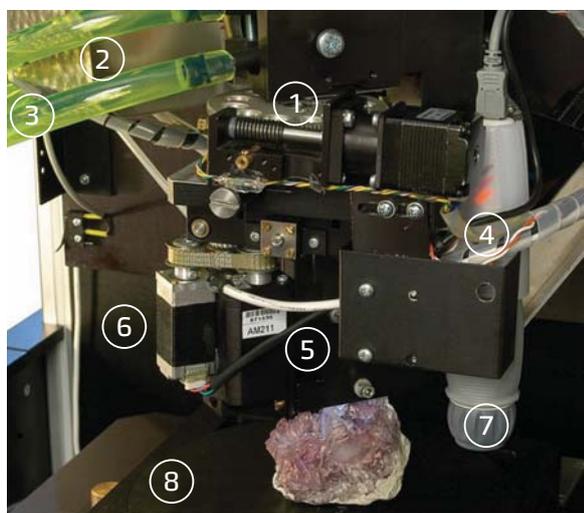
## Software:

- **system control**  
high-voltage generator  
sample and beam positioning  
vacuum
- **local elemental analysis and elemental mapping**  
calibration with single certified sample  
calibration curve with several certified samples  
determination of energy and intensities of characteristic lines  
qualitative and semi-quantitative analysis (fundamental parameter method)  
spectra comparing and searching for analogs from the spectra library  
element mapping of user-defined sample area  
spectra and mapping results storing to data file  
comparison, subtraction, normalization of the stored spectra  
overlay spectra mapping image results on optical and radiographic images  
automatic analysis at user-defined points of sample
- **radiography**  
digital brightness and contrast control  
zooming  
measurement of distance between image points
- **logging and data storage**  
storing images in a database  
saving measurement results and export to other Windows programs  
digitized images record to external media  
images and protocols printing



## Design:

Moving along Z axis with  
an accuracy of 12  $\mu\text{m}$



- 1 block of primary radiation changeable filters (12 filters)
- 2 x-ray tube
- 3 built-in water cooling system
- 4 silicon drift detector
- 5 review video camera
- 6 optical microscope axis combined with the axis of the microprobe (automatic adjustment of sharpness)
- 7 optical microscope (manual adjustment of sharpness)
- 8 sample X,Y – stage with an accuracy of 10  $\mu\text{m}$

## Configuration:

Beam source	
<b>Microfocus X-ray tube:</b> <ul style="list-style-type: none"> <li>X-ray tube max. voltage</li> <li>X-ray tube max. power</li> <li>anode material</li> </ul>	45 kV 500 W Mo, other by request
<b>Polycapillary lens for x-ray beamforming with a variable size of beam</b> <ul style="list-style-type: none"> <li>X-ray beam diameter</li> </ul>	30-1 000 µm
<b>Set of primary beam filters</b>	Zr, Ti, Mo, Ag, Al, Cu, Cl

Optical study	
<b>Optical digital microscope:</b> <ul style="list-style-type: none"> <li>max. zoom</li> </ul>	200x

Sample positioning and mapping	
<b>Video camera to select the area of analysis</b>	
<b>Optical microscope combined with the axis of the X-ray probe to control the area of analysis</b>	
<b>Sample and probe moving system:</b> <ul style="list-style-type: none"> <li>automated system for the working distance selection</li> <li>analytical unit moving along Z axis               <ul style="list-style-type: none"> <li>Z positioning accuracy</li> </ul> </li> <li>automated stage for XY object positioning and scanning over a user-defined sample area               <ul style="list-style-type: none"> <li>XY positioning accuracy</li> </ul> </li> <li>max. scan area</li> <li>sample max. size</li> <li>sample max. weight</li> </ul>	12 µm  10 µm 150x150 mm 300x210x100 mm 1 kg

X-ray fluorescence analysis	
<b>Energy-dispersive semiconductor detector for local elemental analysis:</b>	
<ul style="list-style-type: none"> <li>silicon drift detector (SDD)</li> <li>energy resolution of the detector on the Mn line K<math>\alpha</math></li> <li>spectral range</li> <li>max. counting rate</li> <li>concentration range</li> </ul>	<150 eV 1 - 40 keV 1 000 000 cps from 1 ppm to 100%

Radiography	
<b>Point detector of transmitted through the sample radiation for radiographic studies (optionally CCD detector)</b>	

Analytical unit	
Power supply	230 V, 50 Hz
Size (W x D x H)	615 x 665 x 650 mm
Weight	85 kg